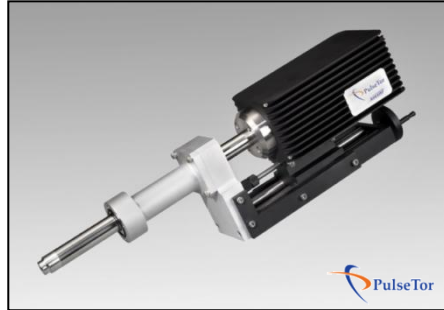


EDX-8100 based on SDD

EDX Microanalysis

for SEM and Microprobes



EDX-8100 is a high performance EDX detector based on Silicon Drift Detector.

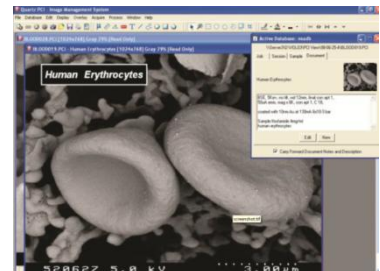
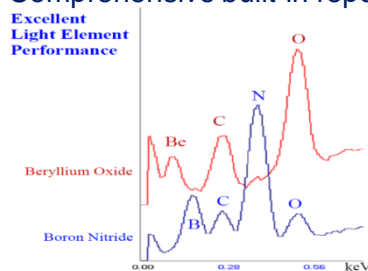
Detector

- 129 eV Resolution without Liquid Nitrogen
- Capable of 10-X Increased Data Throughput at elevated beam currents thanks to SDD and Digital Pulse Processor
- Superior P/B at Low Energies
- Ultra-thin Window for Efficient Light Element Analysis
- High Precision/High Stability Power Supply
- Plug-and-Play connection to new and existing EDX systems
- "On X" solution: a miniaturized Electron Back Scattered Detector (based on scintillator on SiPM technology [1]) directly onto the EDX detector.

[1] "Scintillator on Silicon Photomultiplier Coupled Pair Backscattered Electron Detector", N. Barbi (PulseTor LLC), Microscopy and Microanalysis 2011, Nashville, TN, USA

Software

- Automatic peak identification.
- Analysis by ZAF and Phi-Rho-Z matrix correction routines, stoichiometry, fixed concentration or by difference.
- Quantify by standardless, partial standards or full standards techniques.
- Full spectral imaging. All x-ray events at every pixel are stored by the computer.
- Full live-time correction at every pixel.
- Elements for mapping may be selected before, during or after data acquisition.
- Maps generated with multiple sweeps of the beam. Allows user to see map developing over time.
- Generation of spectrum from any user-specified point or region in map.
- Simultaneous acquisition of SEM image.
- Workgroup Database included as a standard feature.
- Comprehensive built-in report editor.



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